



SLOVENSKI STANDARD

oSIST prEN IEC 62496-2-6:2026

01-februar-2026

Plošče z optičnimi vezji - 2-6. del: Osnovni preskusni in merilni postopki - Analiza vzorca bližnjega polja mnogorodovnih optičnih valovodov s pravokotnim jedrom (jedri) z uporabo metodologije obkroženega toka

Optical circuit boards - Part 2-6: Basic test and measurement procedures - Near field pattern analysis of multimode optical waveguides with rectangular core(s) using encircled flux methodology

iTeh Standards

(<https://standards.iteh.ai>)

Cartes à circuits optiques - Partie 2-6: Procédures fondamentales d'essais et de mesures - Analyse de diagrammes de rayonnement en champ proche de guides d'ondes optiques multimodales à cœurs rectangulaires en utilisant la méthodologie du flux inscrit

[oSIST prEN IEC 62496-2-6:2026](https://standards.iteh.ai/en/standards/osist-pr-en-iec-62496-2-6-2026)

<https://standards.iteh.ai/en/standards/osist-pr-en-iec-62496-2-6-2026> Ta slovenski standard je istoveten z: [prEN IEC 62496-2-6:2026](https://standards.iteh.ai/en/standards/osist-pr-en-iec-62496-2-6-2026)

ICS:

31.180	Tiskana vezja (TIV) in tiskane plošče	Printed circuits and boards
33.180.01	Sistemi z optičnimi vlakni na splošno	Fibre optic systems in general

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86/669/CDV

COMMITTEE DRAFT FOR VOTE (CDV)

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IEC TC 86 : FIBRE OPTICS	
SECRETARIAT: United States of America	SECRETARY: Mr Peter Pondillo
OF INTEREST TO THE FOLLOWING COMMITTEES: SC 86A, SC 86B, SC 86C	HORIZONTAL FUNCTION(S):
ASPECTS CONCERNED:	
☒ SUBMITTED FOR CENELEC PARALLEL VOTING Attention IEC-CENELEC parallel voting The attention of IEC National Committees, members of CENELEC, is drawn to the fact that this Committee Draft for Vote (CDV) is submitted for parallel voting. The CENELEC members are invited to vote through the CENELEC online voting system.	☐ NOT SUBMITTED FOR CENELEC PARALLEL VOTING

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TITLE:

Optical circuit boards – Part 2-6: Basic test and measurement procedures – Near field pattern analysis of multimode optical waveguides with rectangular core(s) using encircled flux methodology

PROPOSED STABILITY DATE: 2029

NOTE FROM TC/SC OFFICERS:

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